Special Issue

Recent Advances in RF MEMS

Message from the Guest Editor

The radio frequency microelectromechanical system (RF MEMS) has been one of the most important applications of MEMS technologies and has long been a research hotspot since the 1990s. Facing the challenges posted by 5G and Internet of Things (IoT), RF MEMSs have shown great potential in wireless applications due to their low cost, low power consumption and excellent RF performance. This Special Issue seeks to focus on RF MEMS devices and systems. We would like to invite you to contribute reviews, new discoveries, and authentic results to participate in this great event. Areas of interest for this Special Issue include designs, fabrications, novel applications, packaging techniques and challenges, material developments, as well as reliability, for RF MEMSs. We look forward to receiving your submissions!

Guest Editor

Prof. Dr. Guoqiang Wu
The Institute of Technological Sciences, Wuhan University, Wuhan 430072, China

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Micromachines
Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
micromachines@mdpi.com

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Editor-in-Chief

Prof. Dr. Ai-Qun Liu
1. Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China
2. School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

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